

ABSTRACT OF THE DISCLOSURE

The invention, which relates to a method for testing movement-sensitive substrates, in which a substrate is mounted on a chuck and makes contact with contact-making needles, and relates to an apparatus which is provided with a chuck which is connected to a positioning apparatus and has contact needles, is based on the object of allowing testing of physical characteristics relating to the mechanical dynamic response of movement-sensitive substrates. This object is achieved in that the substrate is mechanically accelerated during the determination of the physical characteristics. The chuck in this case comprises a lower chuck member and an upper chuck member, with the two chuck members are arranged to move relative to one another, and with at least one movement element being arranged between the two chuck members.